Session Title:	[TuG1] Frontier Metrology and Modeling I
Session Date:	November 12 (Tue.), 2024
Session Time:	13:00-14:25
Session Room:	Room G (Meeting Room, 5F, Grand Josun Busan)
Session Chair:	Prof. Hyungtak Seo (Ajou Univ., Korea)

[TuG1-1] [Plenary] 13:00-13:45

Process Optimization and Control in Dry Etch

Ye Feng (Intel, USA)

[TuG1-2] 13:45-14:05

Etch Rate Uniformity Monitoring for Photoresist Etch Using Multi-Channel Optical Emission Spectroscopy in an Inductively Coupled Plasma Reactor

Sang Hee Han, Sanghoon Lee, Jaehyeon Kim, Eunchong Park, and Heeyeop Chae (Sungkyunkwan Univ., Korea)

[TuG1-3] 14:05-14:25

Measuring Electrical Resistivity of p-Type Si Wafer with Low Dopant Concentration and Its Dependence on Thermal Donor Formation and Surface Treatments

Seob Shim, Gyuhyeok Choi, Mingyu Park, and Woosung Lee (SK Siltron, Korea)